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ABSTRACT OF THE DISCLOSURE

[0026] Monitoring semiconductor wafer tilt, such as in conjunction with semiconductor fabrication equipment having a cooling and or a heating plate, is disclosed. A system for such monitoring includes one or more light sources and one or more light detectors. Each light source generates light that is reflected by the semiconductor wafer. Each light detector senses a detected light value of the light reflected by the semiconductor wafer. If the detected light value deviates from a normal value corresponding to no wafer tilt, then this indicates that the semiconductor wafer has tilted.

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